

<b>Notice of References Cited</b>	Application/Control No. 10/658,466	Applicant(s)/Patent Under Reexamination SHIRAISHI ET AL.	
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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Choi, S.W., Choi, W.B., Lee, Y.H., Ju, B.K., Sung, M.Y., Kim, B.H., "The Analysis of Oxygen Plasma Pretreatment for Improving Anodic Bonding", Journal of the Electrochemical Society, 149 (1) G8-G11 (2002). NOTE: Available Electronically November 20, 2001.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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